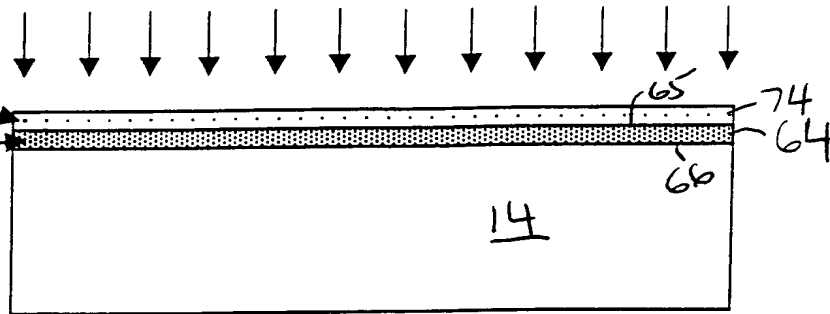


a-Si layer
SiGe layer after
recrystallization



excimer laser beam

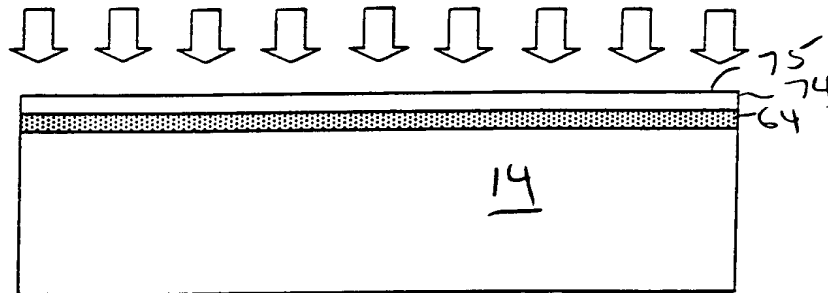


Figure 6

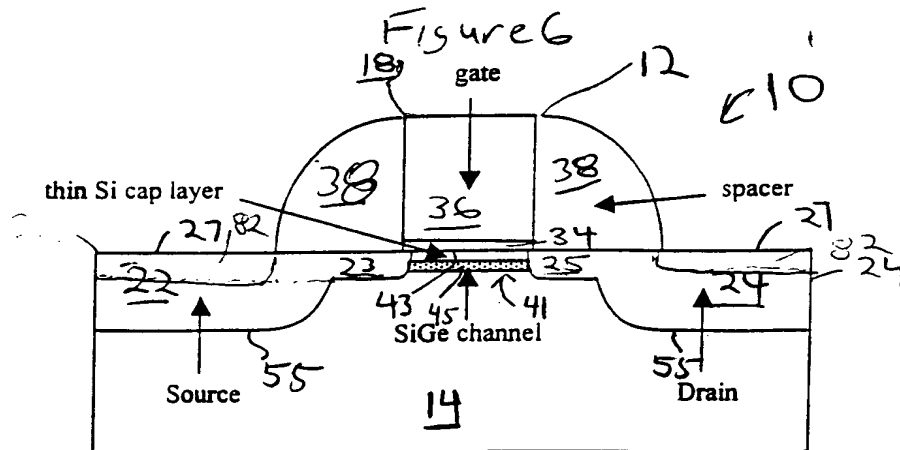


Figure 1

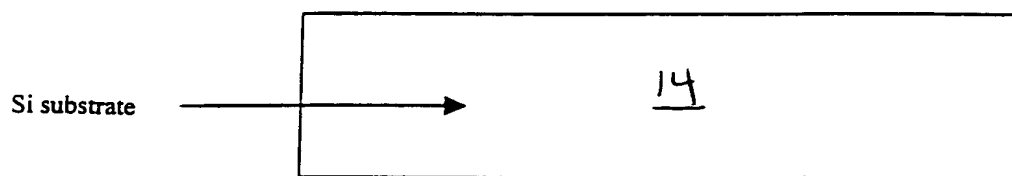


Figure 2

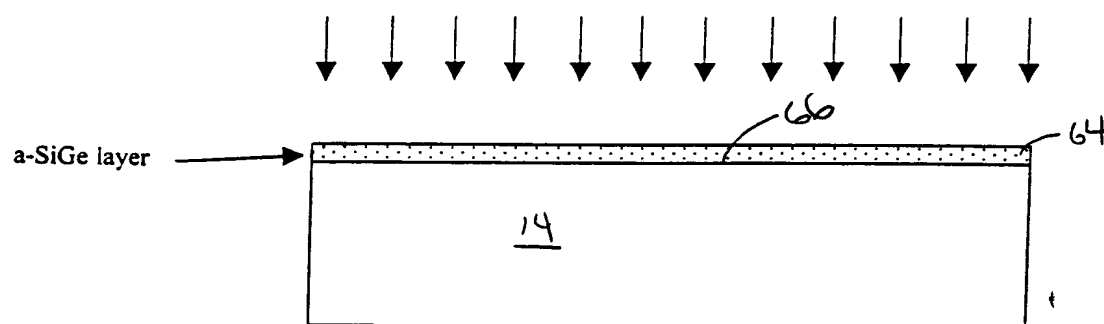


Figure 3

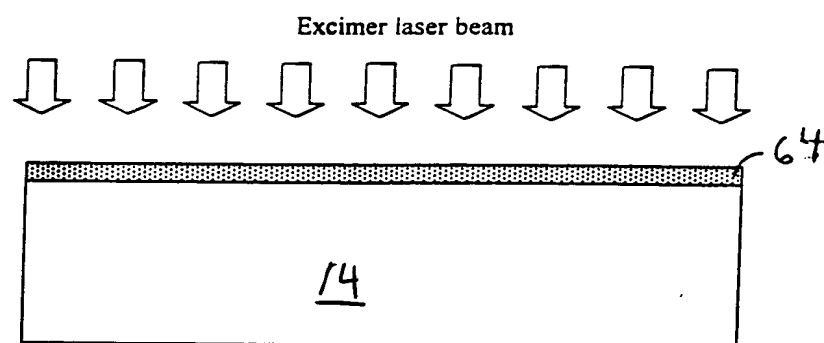


Figure 4